

Supporting Information

High performance pressure/strain sensors featuring conductive network constructed by c-MWCNTs and microspheres for human activity monitoring

Haonan Cheng^{1, 2}, Ningyi Zhang¹, Yunjie Yin¹ and Chaoxia Wang^{1*}

1. College of Textile Science and Engineering, Ministry of Education Jiangnan University, Wuxi, 214122, People's Republic of China.
2. Jiangxi Centre for Modern Apparel Engineering and Technology, Jiangxi Institute of Fashion Technology, Nanchang, 330201, People's Republic of China.

Email: wangchaoxia@sohu.com.



Fig. S1 The measurement platform for sensing performance.

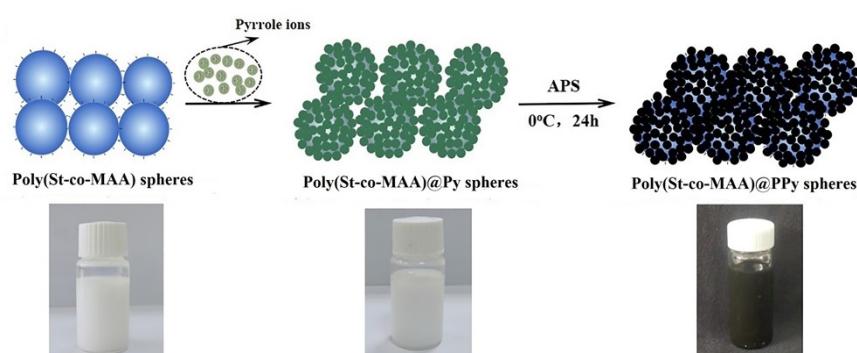


Fig.S2 Diagrams of fabrication process of PPNs.

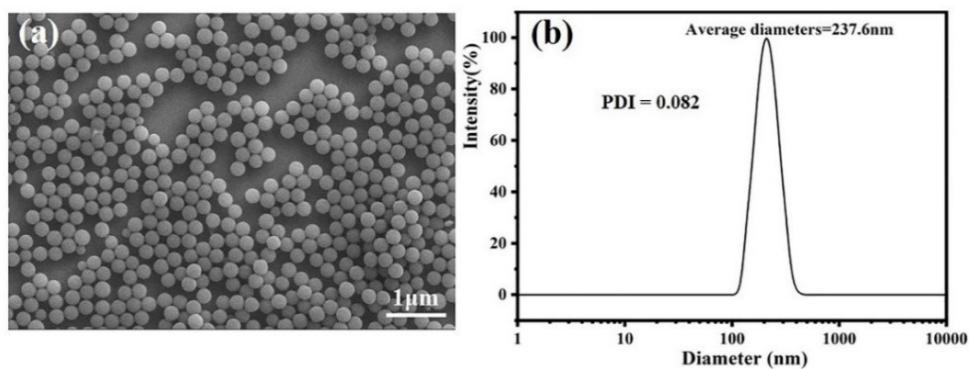


Fig. S3 (a)Scanning electron microscope characterization of P(St-MAA) nanospheres, (b)Particle size distribution of P(St-MAA) nanospheres.

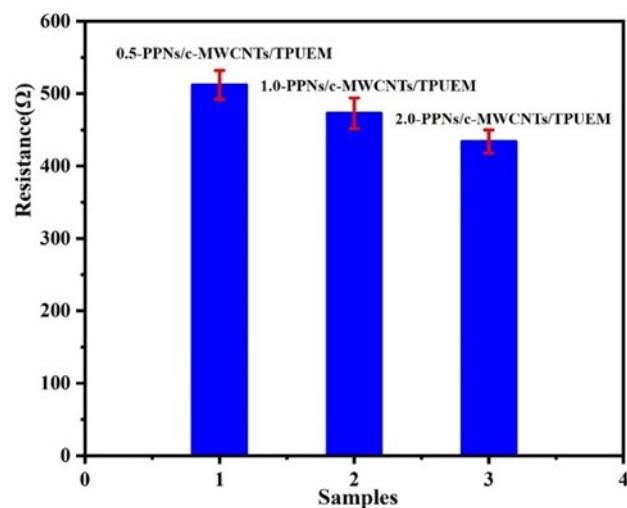


Fig. S4 The electrical conductivity of the PPNS/c-MWCNTs/TPUEM.

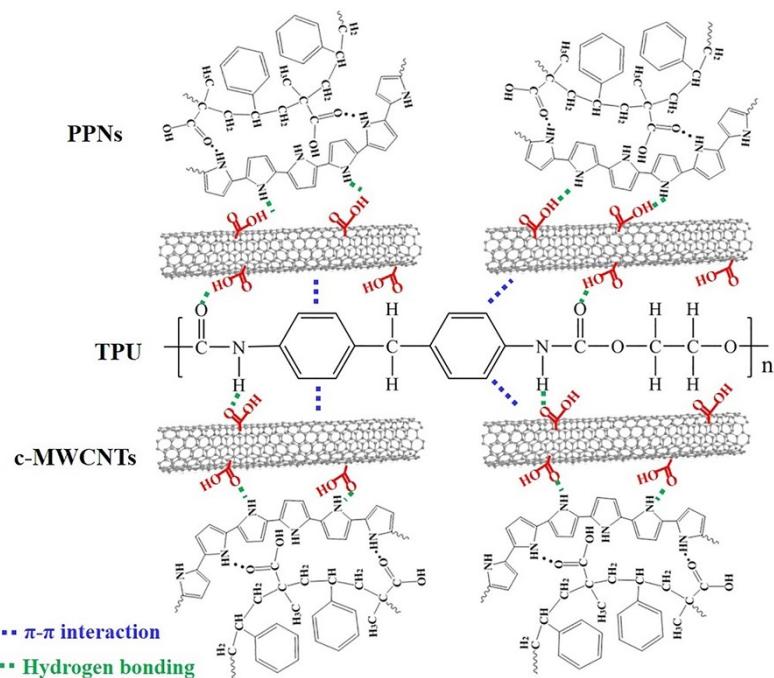


Fig. S5 Schematic diagram of the adsorption interaction among TPU, c-MWCNTs and PPNs.

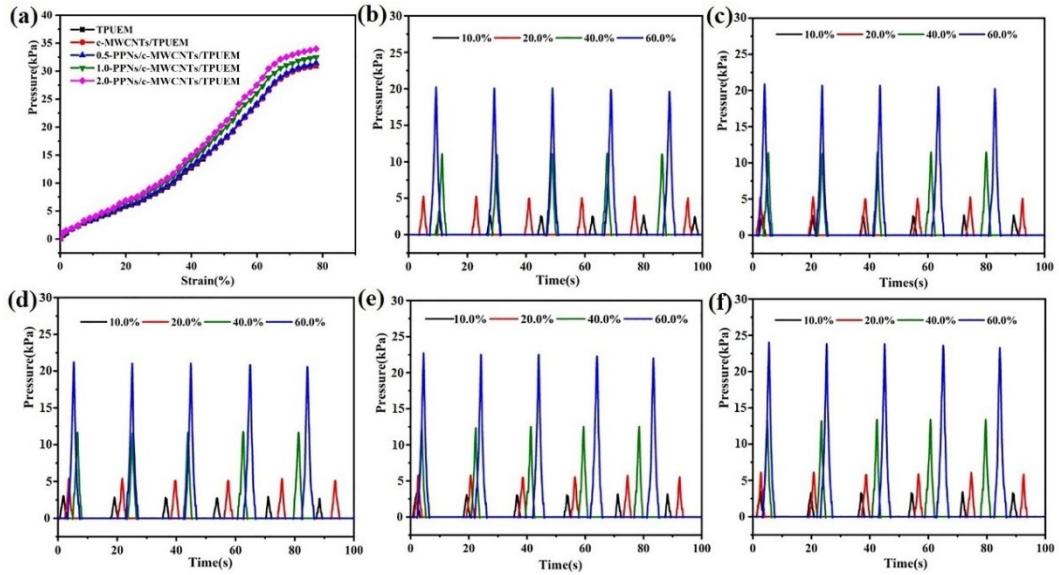


Fig.S6 (a) Stress–strain curves of samples ($8.0\text{mm}\times 7.0\text{mm}$; strain rate=1.5mm/min). Cyclic compression-release curves of samples at strain amplitudes of 10.0%, 20.0%, 40.0% and 60.0%, respectively. (b) TPUEM, (c) c-MWCNTs/TPUEM, (d) 0.5-PPNs/c-MWCNTs/TPUEM, (e) 1.0-PPNs/ c-MWCNTs/TPUEM, and (f) 2.0-PPNs/c-MWCNTs/TPUEM.

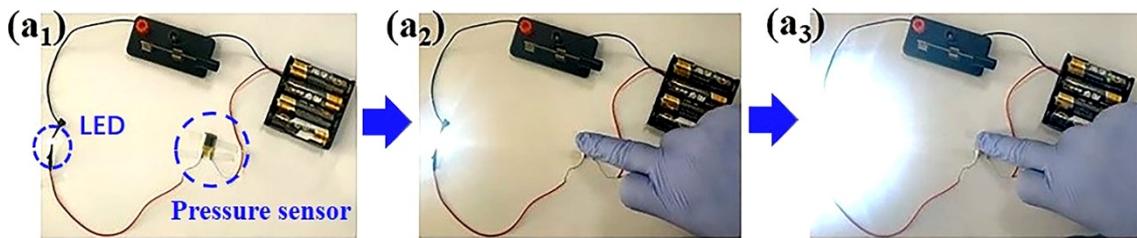


Fig. S7 piezoresistive characteristic of 2.0-PPNs/c-MWCNTs/TPUEM pressure sensor.

Table S1 Comparison of sensitive performance among PDMS/PPMs/c-MWCNTs/TPUEM pressure sensors.

Samples	Sensitivity (kPa ⁻¹)	Response time (ms)	Recovery time (ms)
0.5-PPNs/c-MWCNTs /TPUEM	1.07(0~ 8.18 kPa); 4.78 (8.18~27.68 kPa); 0.63(27.68 ~32.53 kPa)	265	189
1.0-PPNs/c-MWCNTs /TPUEM	3.81(0~ 8.18 kPa); 8.33 (8.18~27.68 kPa); 1.00(27.68 ~32.00 kPa)	230	182
2.0-PPNs/c-MWCNTs /TPUEM	9.03(0~8.18 kPa); 14.16 (8.18~27.68 kPa); 1.64(27.68 ~32.98 kPa)	223	175

Table S2 Comparison of sensitive performance among recently reported flexible pressure sensor based on electrospun membrane.

Samples	Device performance					Ref
	Pressure sensing range (kPa)	Maximum sensitivity (kPa^{-1})	Response time (ms)	Stability (cycles)		
CNTs-PVDF/PVA electrospun membrane	~ 200.0	0.023 (0~25 kPa)	—	350	30	
Fe ₃ O ₄ /carbon PAN electrospun membrane	~5.0	0.545(0~1.0 kPa)	430	505	31	
Bi ₂ S ₃ /PPy/PVDF electrospun membrane	~ 60.0	1.51 (0~60.0kPa)	40	5000	32	
PEDOT:PSS/PVDF electrospun membrane	~30.0	13.50(0~5.2 kPa)	—	10000	33	
c-MWCNTs/TPU electrospun membrane	~10.0	2.0 (0~1.0 kPa)	70	1000	14	
PPNs/rGO/TPUEM	~62.5	13.65(0~3.75 Pa)	37	1650	10	
MXene/cellulose nonwoven fabrics	~ 17.4	28.723 (3.266~12.2 kPa)	500	—	34	
PDMS/2.0-PPNs/c-MWCNTs /TPUEM	~32.98	14.16 (8.18~27.68 kPa)	223	1800	This work	

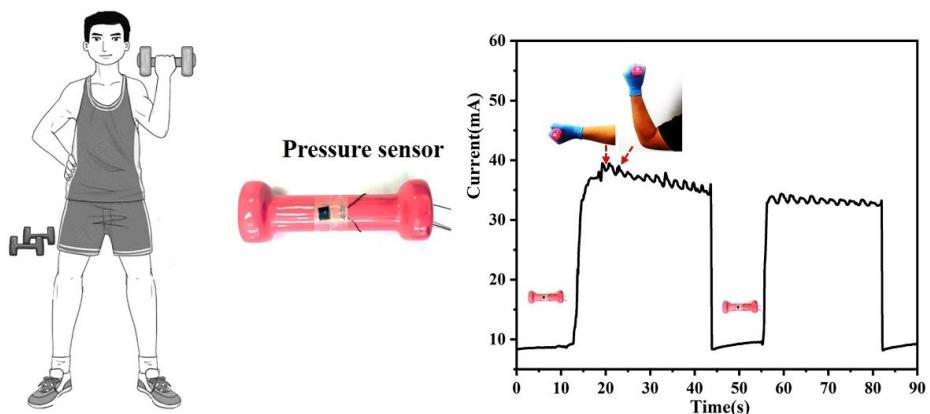


Fig. S8 Demonstration of the pressure sensor in human motion detection.

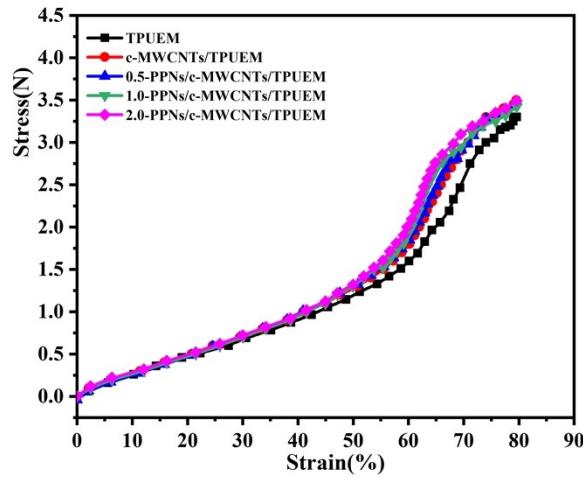


Fig.S9 The compressive stress–strain curves of TPUEM, c-MWCNTs/TPUEM, and PPNs/c-MWCNTs/TPUEM (40.0mm×13.0mm; Tensile rate=12.0 mm/ min).

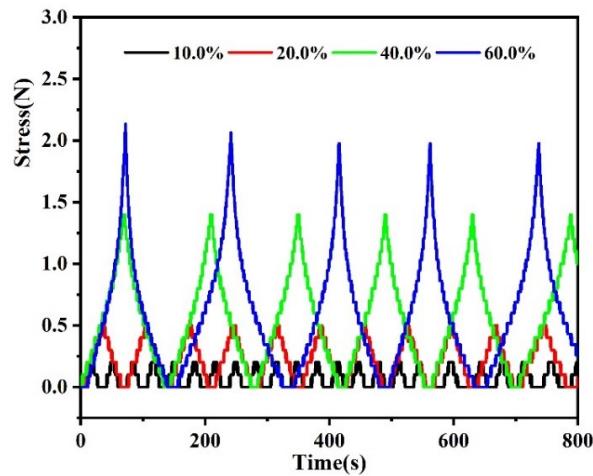


Fig.S10 Stress curves at different compression ratios of PDMS/2.0-PPNs/c-MWCNTs/TPUEM (40.0mm×13.0mm; Tensile rate=12.0 mm/min).

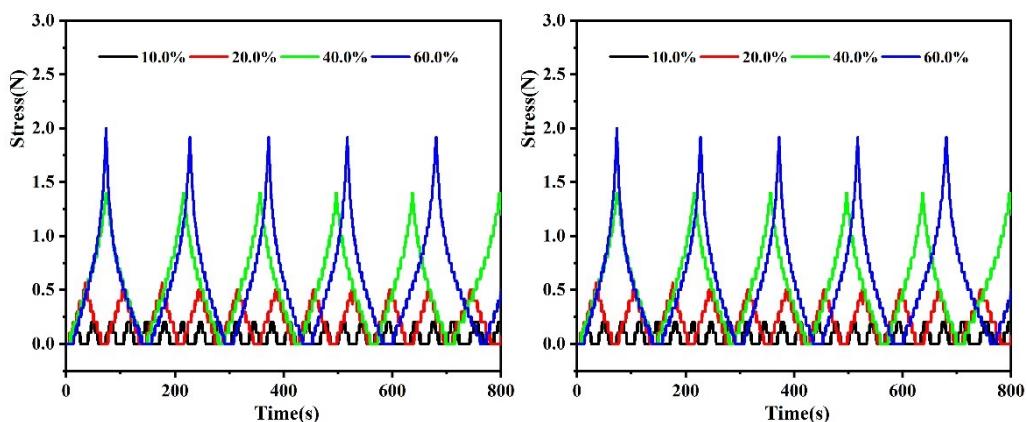


Fig. S11 Stress curves at different compression ratios of PDMS/0.5-PPNs/ c-MWCNTs/TPUEM and PDMS/1.0-PPNs/c-MWCNTs/TPUEM (40.0mm×13.0 mm; Tensile rate=12.0 mm/min).

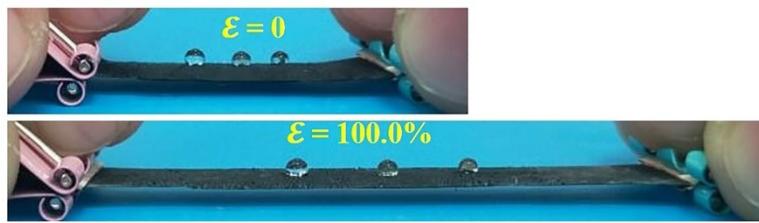


Fig. S12 Photos of droplets (water, orangeade and green tea) standing on the hydrophobic surface of PDMS/2.0-PPMs/c-MWCNTs/TPUEM under 100.0% strain.

Table S3. Comparison of sensitive performance among recently reported flexible strain sensor based on TPUEM.

Samples	Device performance				Ref
	Strain sensing range (%)	Maximum GF	Stability (cycles)		
CNTs/TPUEM	~900.0	19.96(600.0~900.0 %)	10000	35	
PDA/rGO/TPUEM	~100.0	23.3(~60.0 %)	100	36	
PDMS/AgNWs/TPUEM	~150.0	12.9(0~20.0 %)	800	37	
PFDT/PDA/graphene/TPUEM	~100.0	5.9(0~20.0 %)	1000	38	
PDMS/CNTs-50/TPUEM	~100.0	0.34(50.0~100.0 %)	700	18	
PDMS/2.0-PPMs/c-MWCNTs /TPUEM	~100	2.03(94.3~100.0 %)	650	This work	

MovieS1 Monitoring of finger bending using PDMS/2.0-PPNs/c-MWCNTs/TPUEM strain sensor.